FORM PTO-1449 (modified) To: U.S. Department of Commerce (PW FORM PAT-1449) Patent and Trademark Office	Atty. Dkt. No.	M#		Client Ref.
INFORMATION DISCLOSURE STATEMENT BY APPLICANT		304500		P-1503.001-US
	Applicant: Steven HANSEN			
Date: November 20, 2003 Page	1	of	1	Appln. No.: TO ~~BE ASSIGNED~~ *10/716,439* Filing Date: November 20, 2003 Examiner: Group Art Unit:

U.S. PATENT DOCUMENTS

Examiner's Initials*		Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
AM	AR	5,305,054	04/1994	SUZUKI et al.		—	
AM	BR	6,049,660	04/2000	AHN et al.		—	
AM	CR	6,452,662	09/2002	MULKENS et al.		—	
AM	DR	6,466,304	10/2002	SMITH		—	
	ER						
	FR						
	GR						
	HR						
	IR						
	JR						
	KR						
	LR						
	MR						
	NR						

FOREIGN PATENT DOCUMENTS

		Document Number	Date MM/YYYY	Country	Inventor Name		English Abstract		Translation Readily Available	
							Enclosed	No	Enclose	No
	OR									
	PR									
	QR									
	RR									
	SR									
	TR									
	UR									
	VR									
	WR									
	XR									

OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)

	YR				
	ZR				
	AAR				
	BBR				
	CCR				
	DDR				

Examiner *Alan Mathews*   Date Considered: *8·5-2005*

*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

OIPE
FEB 2 0 2004

Atty. Dkt. No.	M#		Client Ref.
		304500	P-1503.001-US

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

Applicant: Steven HANSEN

Appln. No.: 10/716,439

Filing Date: November 20, 2003

Date: February 20, 2004   Page 1 of 1   Examiner: Group Art Unit:

U.S. PATENT DOCUMENTS

Examiner's Initials*		Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
AM	AR	5,523,193	06/1996	NELSON			
AM	BR	6,463,403 B1	10/2002	BURDORF et al.			
AM	CR	2002/0035461 A1	03/2002	CHANG et al.			
AM	DR	2002/0045106 A1	04/2002	BASELMANS et al.			
AM	ER	2002/0062206 A1	05/2002	LIEBCHEN			
AM	FR	2002/0152452 A1	10/2002	SOCHA			
AM	GR	2002/0167653 A1	11/2002	MULKENS et al.			
AM	HR	2003/0093251 A2	05/2003	CHANG			
	IR						
	JR						
	KR						
	LR						
	MR						
	NR						

FOREIGN PATENT DOCUMENTS

		Document Number	Date MM/YYYY	Country	Inventor Name		English Abstract		Translation Readily Available	
							Enclosed	No	Enclose	No
	OR									
	PR									
	QR									
	RR									
	SR									
	TR									
	UR									
	VR									
	WR									
	XR									

OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)

YR					
ZR					
AAR					
BBR					
CCR					
DDR					

Examiner: Alan Mathews   Date Considered: 8-6-2005

FORM PTO-1449 (modified) To: U.S. Department of Commerce (PW FORM PAT-1449) Patent and Trademark Office	Atty. Dkt. No.	M#	Client Ref.

OIPE — MAY 10 2004 — PATENT & TRADEMARK OFFICE — JC174

INFORMATION DISCLOSURE STATEMENT BY APPLICANT	304500	P-1503.001-US	
	Applicant: HANSEN		
	Appln. No.: 10/716,439		
	Filing Date: November 20, 2003		
Date: May 10, 2004 Page 1 of 1	Examiner: NOT ASSIGNED	Group Art Unit: ~~2825~~ 2851	

U.S. PATENT DOCUMENTS

Examiner's Initials*		Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
AM	AR	5,680,588	10/1997	Gortych et al.			
AM	BR	2003/0082463 A1	05/2003	Laidig et al.			

FOREIGN PATENT DOCUMENTS

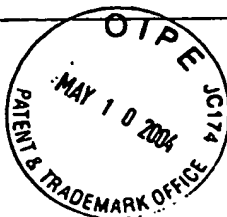|		Document Number	Date MM/YYYY	Country	Inventor Name		English Abstract		Translation Readily Available	
							Enclosed	No	Enclose	No
	CR									

OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)

AM	DR	Burkhardt et al., "Illuminator Design for the Printing of Regular Contact Patterns," *Microelectronic Engineering*, Vol. 41, No. 42, 1998, pp. 91-96.					
	ER	Chen et al., "Practical Method for Full-Chip Optical Proximity Correction," *SPIE*, Vol. 3051, 1997, pp. 790-803.					
	FR	Chen et al., "Optical Proximity Correction for Intermediate-Pitch Features Using Sub-Resolution Scattering Bars," *Journal of Vacuum Science & Technology B*," Vol. 15, No. 6, Nov/Dec 1997, pp. 2426-2433.					
	GR	Flagello et al., "Lithographic Lens Testing: Analysis of Measured Aerial Images, Interferometric Data and Photoresist Measurements," *SPIE Microlithography Seminar*, 1996.					
	HR	Flagello et al., "Towards a Comprehensive Control of Full-Field Image Quality in Optical Photolithography," *SPIE Microlithography Seminar*, March 1997.					
	IR	Gau et al., "Strategy to Manipulate the Optical Proximity Effect by Post-Exposure Bake Processing," *SPIE*, Vol. 3334, 1998, pp. 885-891.					
	JR	Gau et al., "The Customized Illumination Aperture Filter for Low k1 Photolithography Process," *SPIE*, Vol. 4000, March 2000, pp. 271-282.					
	KR	Hsia et al., "Customized Off-Axis Illumination Aperture Filtering for Sub-0.18 μm KrF Lithography," *SPIE*, Vol. 3679, March 1999, pp. 427-434.					
	LR	Liu et al., "The Application of Alternating Phase-Shifting Masks to 140 nm Gate Patterning: Line Width Control Improvements and Design Optimization," *SPIE*, Vol. 3236, 1998, pp. 328-337.					
	MR	Smith et al., "Illumination Pupil Filtering Using Modified Quadrupole Apertures," *SPIE*, Vol. 3334, 1998, pp. 384-394.					
	NR	Suzuki et al., "Multilevel Imaging System Realizing k_1=0.3 Lithography," *SPIE*, Vol. 3679, March 1999, pp. 396-407.					
V	OR	Wong et al., "Level-Specific Lithography Optimization for 1-Gb DRAM," *IEEE Transactions on Semiconductor Manufacturing*, Vol. 13, No. 1, February 2000, pp. 76-87.					

Examiner: Alan Mathews	Date Considered: 8-5-2005

*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

OIPE
MAY 1 0 2004
PATENT & TRADEMARK OFFICE
JC174

APPENDIX

Examiner's Initials	First Inventor	Application No.	Filing Date	Enclosed
A M	Liebchen	10/705,234	November 12, 2003	☒ Specification ☒ Drawings ☒ Other: Claims

The Examiner's initials indicates he/she has considered the cited application relative to the subject application.

(DO NOT PRINT) the above information on the patent which results from the subject application.

Date Considered

8-5-2005

Alan A. Mathew

FORM PTO-1449 (modified) To: U.S. Department of Commerce (PW FORM PAT-1449) Patent and Trademark Office	Atty. Dkt. No.	M#		Client Ref.
INFORMATION DISCLOSURE STATEMENT **BY APPLICANT** AUG 27 2004 Date: August 27, 2004 Page 1 of 1		304500		P-1503.010-US

Applicant: HANSEN

Appln. No.: 10/716,439

Filing Date: November 20, 2003

Examiner: TBA	Group Art Unit: 2825

U.S. PATENT DOCUMENTS

Examiner's Initials*		Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
AM	AR	2003/0073013 A1	04/2003	Hsu et al.			
	BR						
	CR						
	DR						
	ER						
	FR						
	GR						
	HR						
	IR						
	JR						
	KR						
	LR						

FOREIGN PATENT DOCUMENTS

		Document Number	Date MM/YYYY	Country	Inventor Name		English Abstract		Translation Readily Available	
							Enclosed	No	Enclose	No

OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)

	MR					
	NR					
	OR					
	PR					
	QR					
	RR					
	SR					
	TR					
	UR					
	VR					
	WR					
	XR					

Examiner *Alan Mathews*	Date Considered: *8·5·2005*

*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.